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Applicant: Tsuga et al.

Art Unit: 1746

Serial No.: 10/085,725

Examiner: Kornakov, M.

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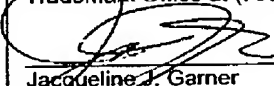
OFFICIAL

Title: METHOD AND DEVICE FOR REMOVING PARTICLES ON
SEMICONDUCTOR WAFERS

AMENDMENT UNDER 37 CFR 1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following papers are being
transmitted by facsimile to the U.S. Patent and
Trademark Office at (703) 872 - 9306 on 6/21/2004.
Jacqueline J. Garner
Reg. No. 36,144

Dear Sir:

The following amendments and remarks are offered in response to the Examiner's Office Action dated 01/20/2004. They are respectfully submitted as a full and complete response to that Action.

Please amend the above-referenced application as follows:

There are no **Amendments to the Specification**.**Amendments to the Claims** are reflected in the listing of claims that begin on page 2 of this paper.There are no **Amendments to the Drawings**.The **Remarks** begin on page 3.